

Lecture 4
of
EEE201

CMOS Digital Integrated Circuits

Department of Electrical & Electronic Engineering
Xi'an Jiaotong-Liverpool University (XJTLU)

Monday, 7th October 2024

□ MOS Capacitor

- physical structure
- operation modes & band diagrams
- capacitance



Module Roadmap

CMOS Digital Integrated Circuit

Technology

Design and Technology Co-Optimization

Design

Material

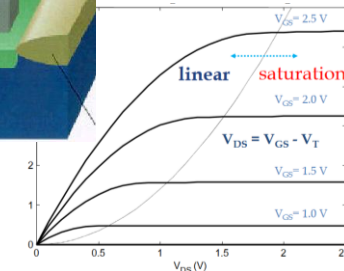
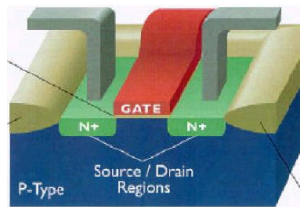
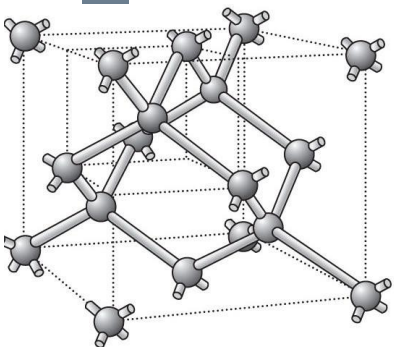
Device

CMOS Circuit

Lecture 4

Silicon

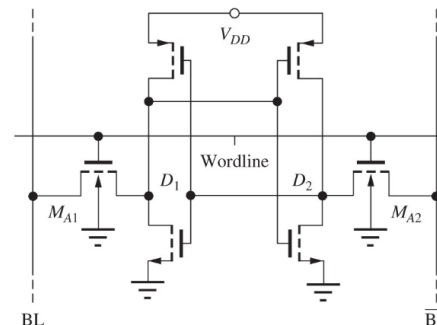
1. Crystal structure
2. Energy diagram
3. Doping
4. Charge carriers
5. Carrier transport



- Device types:**
1. P-N Junction
 2. MOS Capacitor
 3. MOSFET Transistor
 4. MOSFET inverter

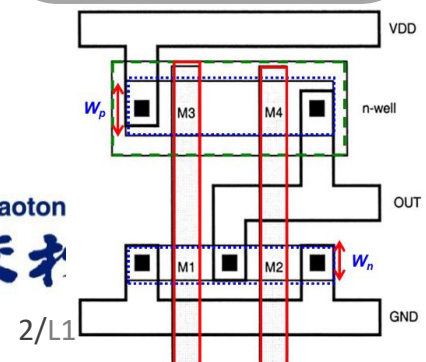
Circuit types:

1. Combinational logic circuits
2. Variant digital IC:
 - pseudo NMOS
 - Memory
 - Dynamic logic



Physical design :

1. Layout design:
 - Physical structures & layout principles
 - Area optimization
2. Physical design of CMOS inverter



Recap: Lecture 3

MOS Transistor: IC Building Blocks

PN Junction

Electrostatic

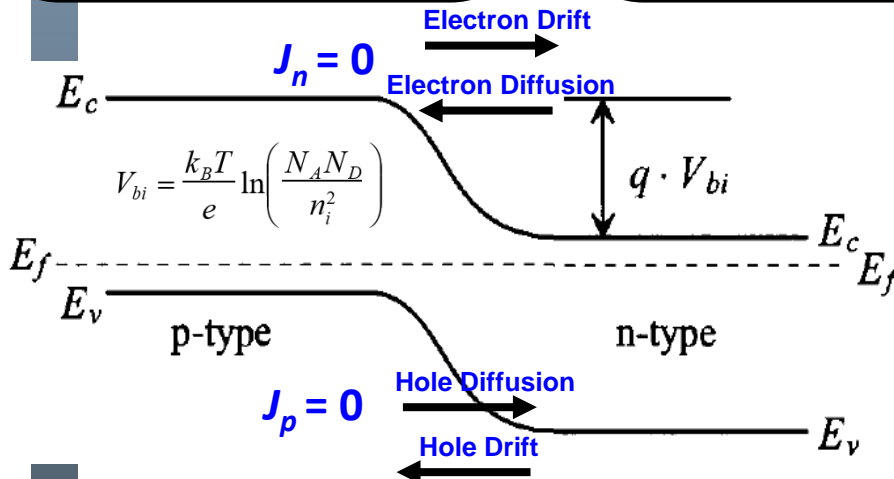
1. Concentration gradient \Rightarrow Diffusion current (J_{diff})
2. Depletion regions (immobile ionized dopant and acceptors) \Rightarrow Drift current (J_{drift})
3. Built-in potential (V_{bi}) to balance J_{diff} and $J_{drift} \Rightarrow$ zero net current at equilibrium.
4. At equilibrium, $J_n = J_p = 0$

Current Characteristics

1. Forward Bias:
 - Dominant Current: Diffusion current of majority carriers.
 - Large current flow through junction
2. Reverse Bias:
 - Dominant Current: Drift current of minority carriers.
 - Small reverse saturation current until breakdown occurs.

Capacitance Characteristics

1. Impacts circuit **dynamics behavior**.
2. Depletion Region as a Capacitor:
 - Depletion regions with fixed charge \Rightarrow electric field and act as the plates of a capacitor.
 - Depletion width \Rightarrow distance between the capacitor plates.
 - Applying a reverse (forward) bias increases (decreases) W , reducing (increasing) capacitance.



$$W_0 = W_p + W_n = \sqrt{\frac{2\epsilon_{Si}(N_A + N_D)V_{bi}}{eN_A N_D}}$$

$$I_D = I_{so} \left[\exp\left(\frac{eV}{k_B T}\right) - 1 \right] \quad C = \frac{\epsilon A}{d} \Rightarrow C_j = \frac{\epsilon_{Si} A_j}{W_0}$$

MOS Capacitor

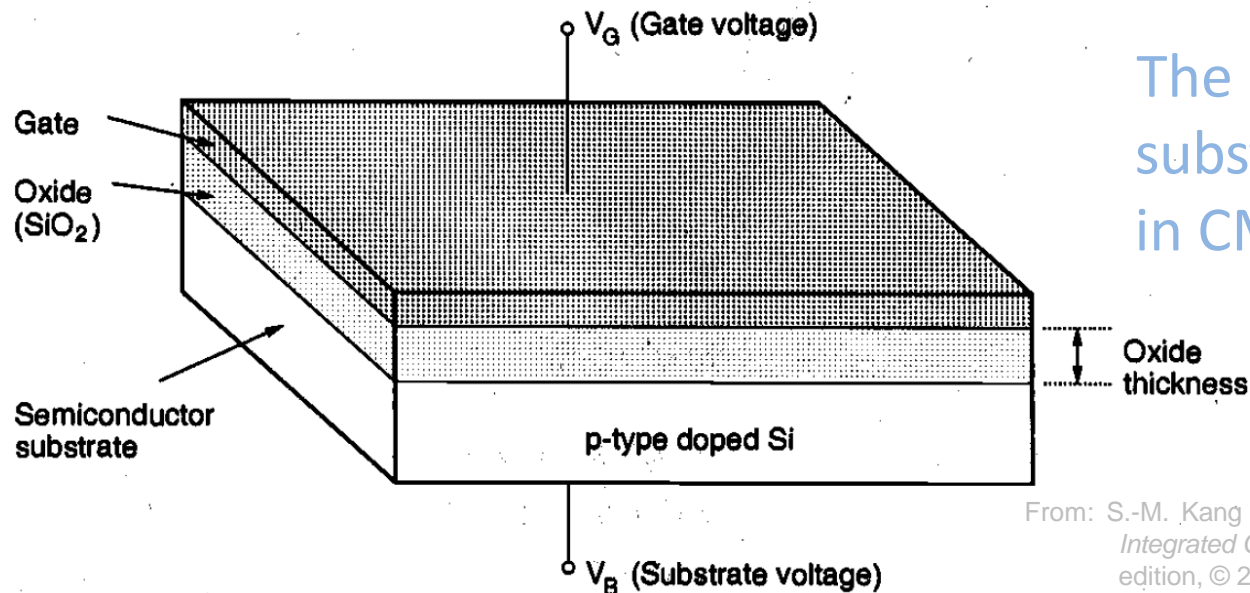
(fundamental to MOS transistor)

- ❑ CMOS digital ICs are constructed predominantly with **MOS transistors**.
- ❑ The **MOS transistor** is based on the **MOS capacitor** which is also a *fundamental* semiconductor structure apart from the ***p-n junction***.
 - The **MOS capacitor** is also a two-terminal device like the ***p-n junction*** diode.
 - Knowledge of the **MOS capacitor** would be helpful to understand the operation and electrical properties of the **MOS transistor** or called the MOSFET.

MOS Capacitor

(3-layered physical structure)

- ❑ The **MOS** capacitor consists of three layers:
 - the **metal** or polysilicon gate electrode
 - the insulating **oxide** (typically SiO_2)



The semiconductor substrate is silicon in CMOS digital ICs.

- the **semiconductor** substrate

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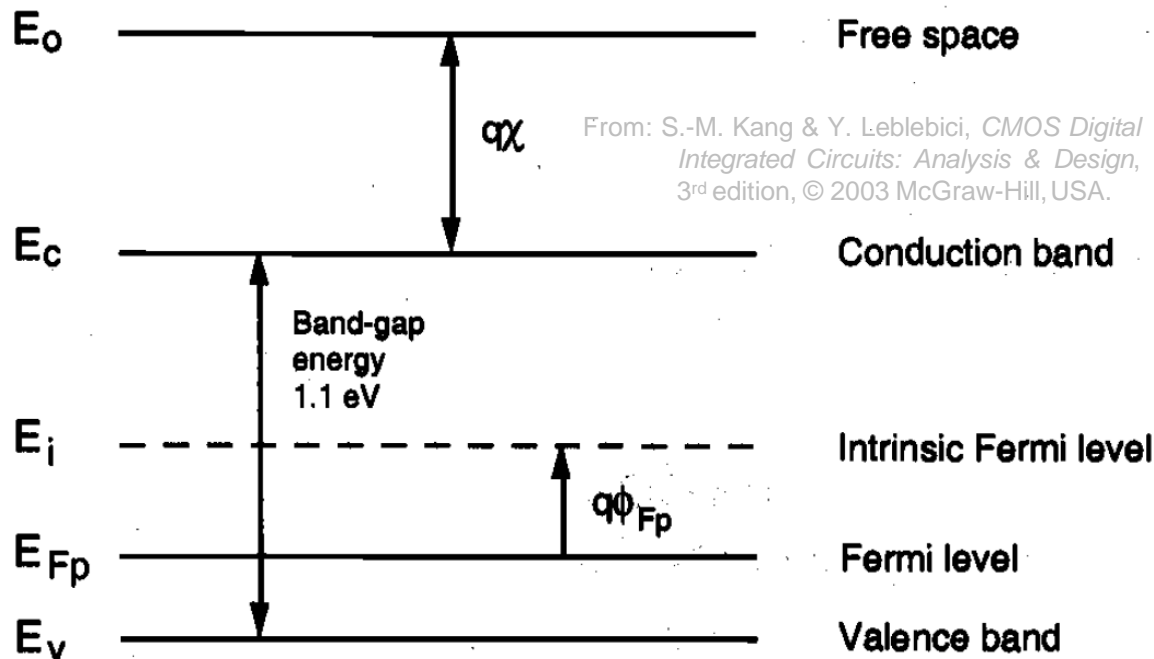


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MOS Capacitor

(band diagram of silicon substrate)

- ❑ An insightful understanding of the MOS capacitor needs to use the electronic **energy band diagrams**.



- Note the **free space energy level** (or called **vacuum level**), where electrons would be set free from the material.

- The above energy band diagram is p-type silicon. (Do you know why?)

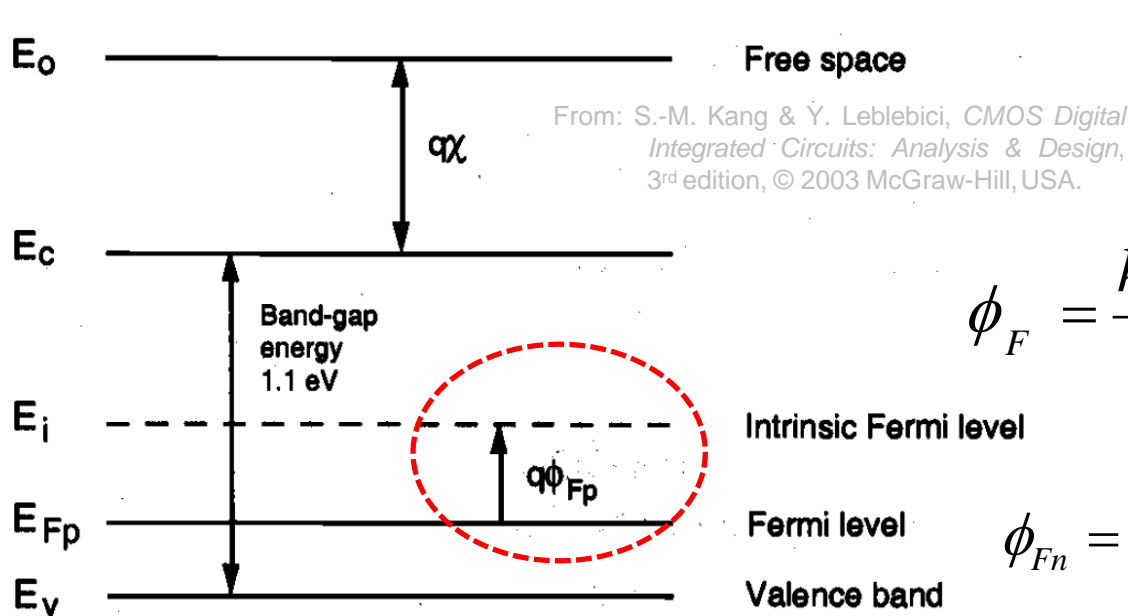


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MOS Capacitor

(Fermi potential ϕ_F)

- In a doped semiconductor, the position of the *equilibrium Fermi level* E_{Fp} (or E_{Fn}) relative to the *intrinsic Fermi level* E_i can be quantified as ϕ_F :



$$\phi_F \equiv \frac{E_F - E_i}{q}$$

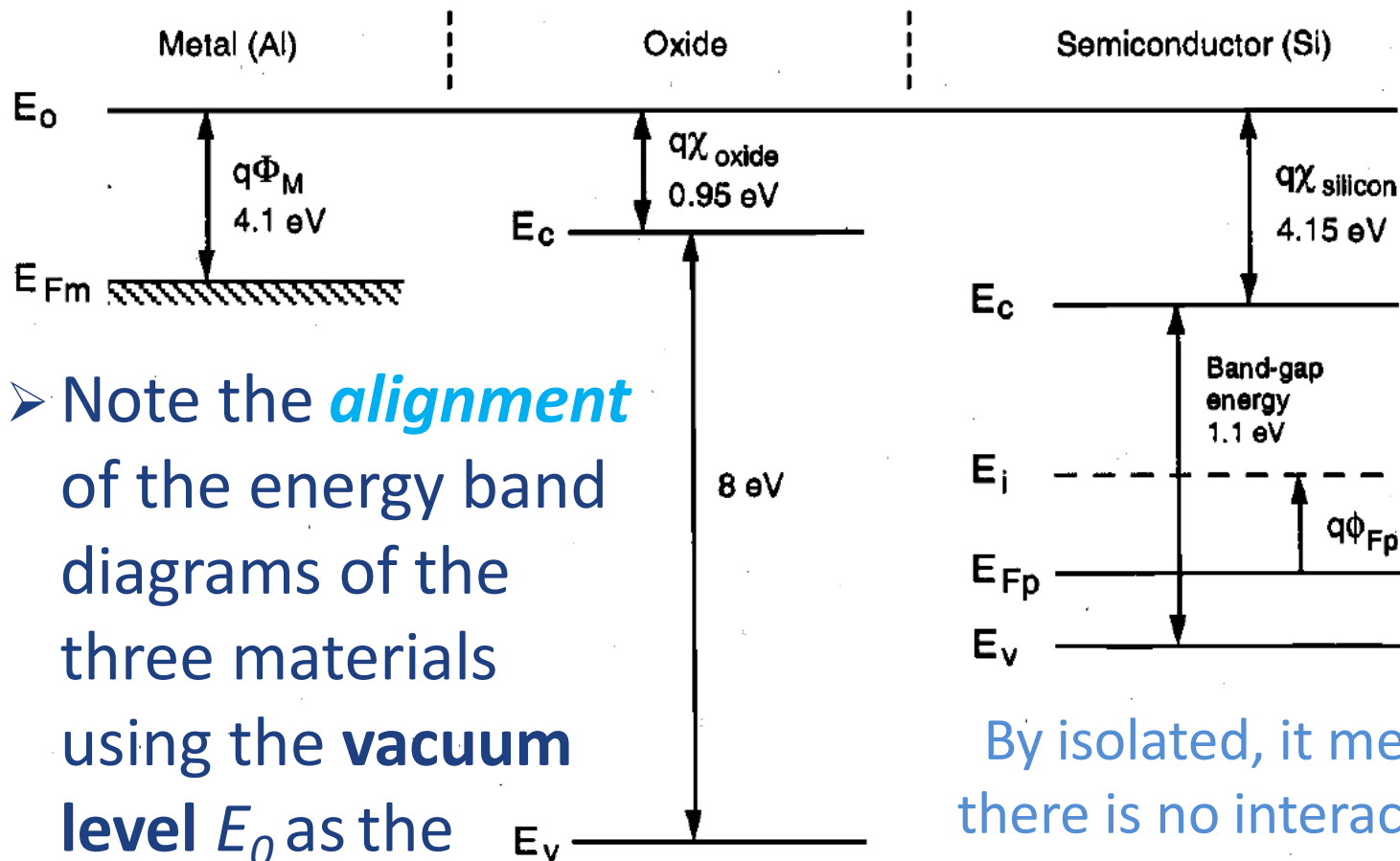
$$\phi_F = \frac{kT}{q} \ln\left(\frac{n_i}{p}\right) \approx \frac{kT}{q} \ln\left(\frac{n_i}{N_A}\right)$$

$$\phi_{Fn} = \frac{kT}{q} \ln\left(\frac{n}{n_i}\right) \approx \frac{kT}{q} \ln\left(\frac{N_D}{n_i}\right)$$

➤ ϕ_F will be used to define **inversion**.

Energy Band Diagram of MOS

(three layers isolated)



➤ Note the **alignment** of the energy band diagrams of the three materials using the **vacuum level E_0** as the reference.

By isolated, it means there is no interaction.

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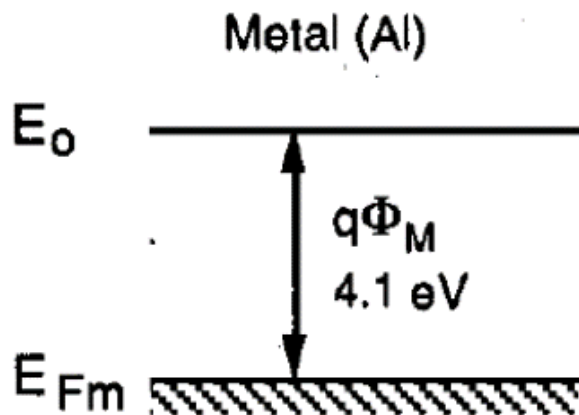
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Metal's Energy Band Diagram

(work function)

- ❑ The energy band diagram of metal consists of the vacuum level E_0 and the Fermi level E_{Fm} .
- ❑ The energy difference between E_0 and E_{Fm} is called the **work function** $q\Phi$.
 - It is the energy required for an electron to set free from the metal.

From: S.-M. Kang & Y. Leblebici, *CMOS Digital Integrated Circuits: Analysis & Design*, 3rd edition, © 2003 McGraw-Hill, USA.



- Note that in metal there are states for electrons at E_{Fm} . In contrast, in semiconductor, E_F is typically in the band gap where there is no state for electrons.

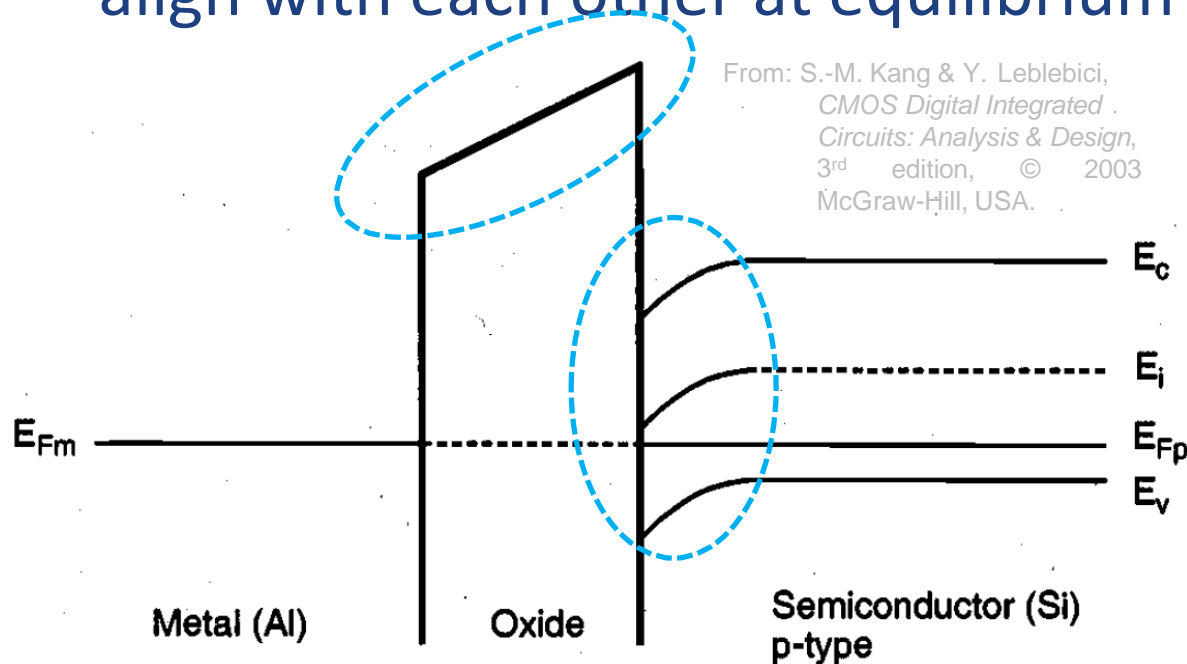


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Energy Band Diagram of MOS

(three layers brought together)

- When the three materials are brought together, the **Fermi levels** of the metal and semiconductor align with each other at equilibrium (open-circuit).



- Note the band bending in the oxide layer and in the surface region of the semiconductor near the oxide.

- What does the band bending mean?

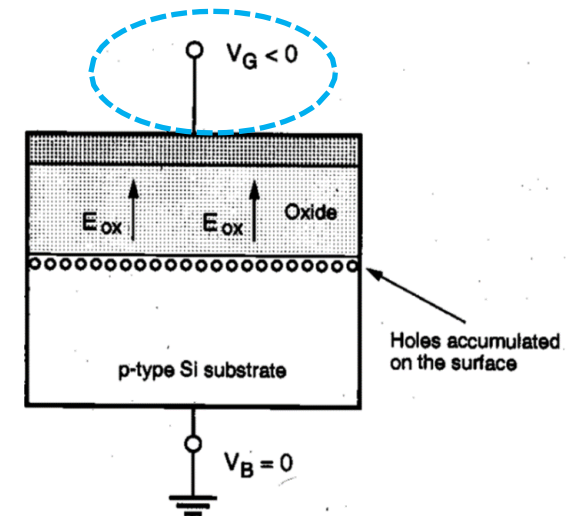
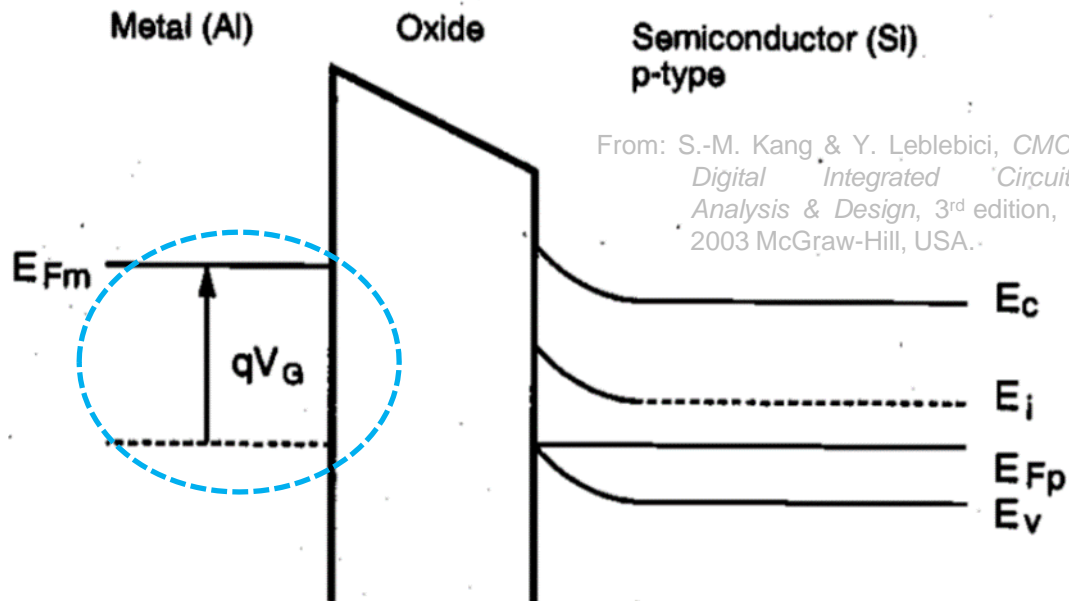


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Energy Band Diagram of MOS

(negative voltage at the gate)

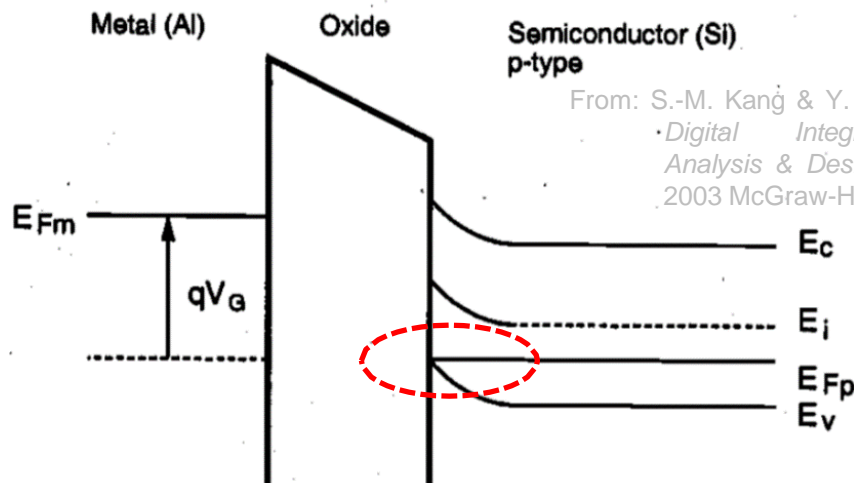
- ❑ The energy band diagram of the MOS capacitor can be changed by an applied gate voltage V_G (assuming the substrate is grounded i.e. $V_B = 0$).
 - negative $V_G \Rightarrow$ raised electronic energy at the gate



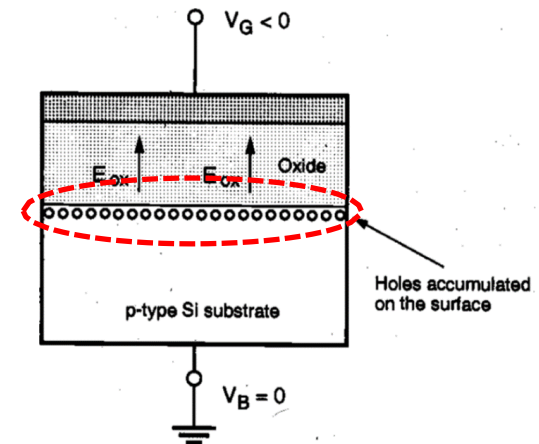
Hole Accumulation

(accumulation mode)

- ❑ With the raised electronic energy at the gate, it causes band-bending in the oxide and in the surface region of the semiconductor.
 - At the semiconductor surface location, E_{Fp} is close to E_v .
 - The hole concentration increases further at the surface.
 - Holes are **accumulated** at the surface.



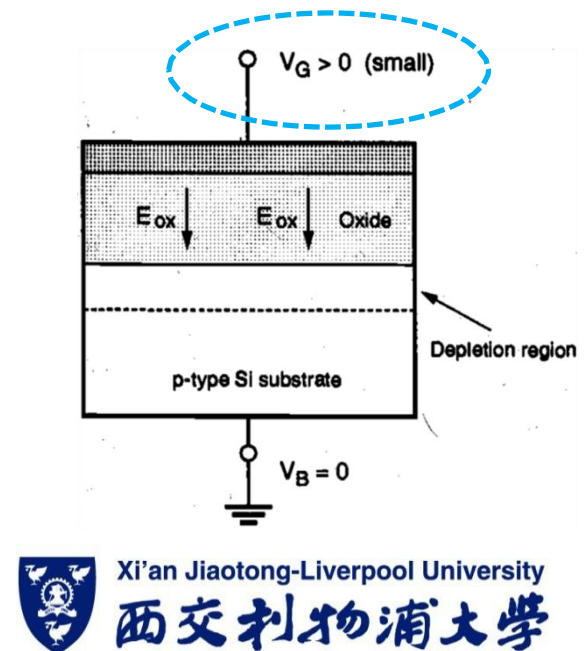
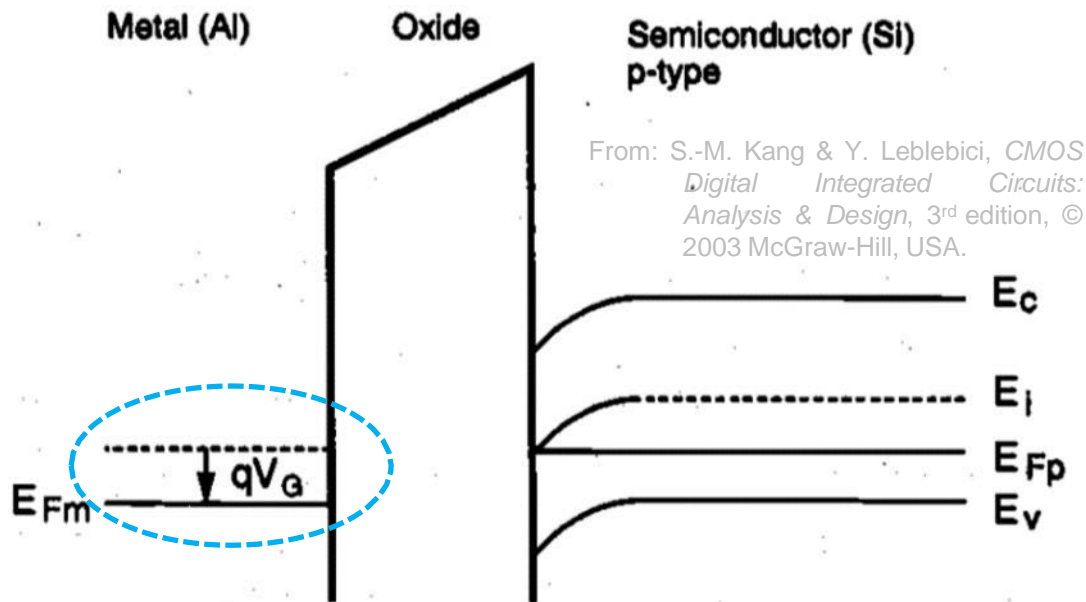
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Energy Band Diagram of MOS

(positive voltage at the gate)

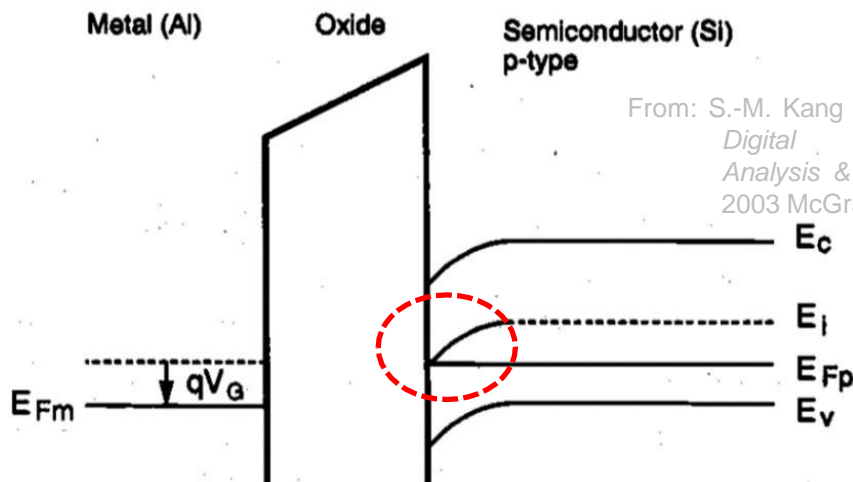
- ❑ If the gate voltage is positive, the electronic energy at the gate is lowered.
 - The metal's Fermi level E_{Fm} is lowered by qV_G from the open-circuit level.



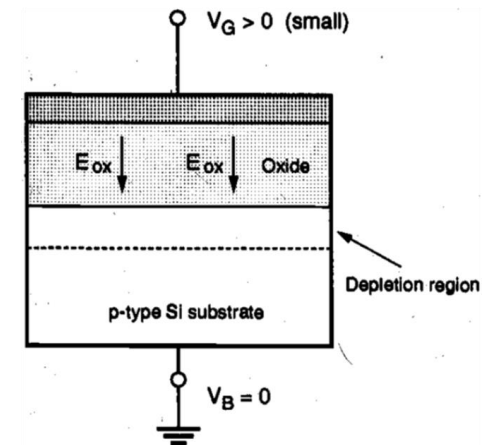
Holes Depleted in Surface Region

(depletion mode)

- ❑ With the electronic energy at the gate lowered, it also causes band-bending in the oxide and in the surface region of the semiconductor.
 - At the semiconductor surface location, $E_{Fp} \approx E_{Fi}$.
 - The hole concentration decreases at the surface location.
 - Holes are **depleted** from the surface.



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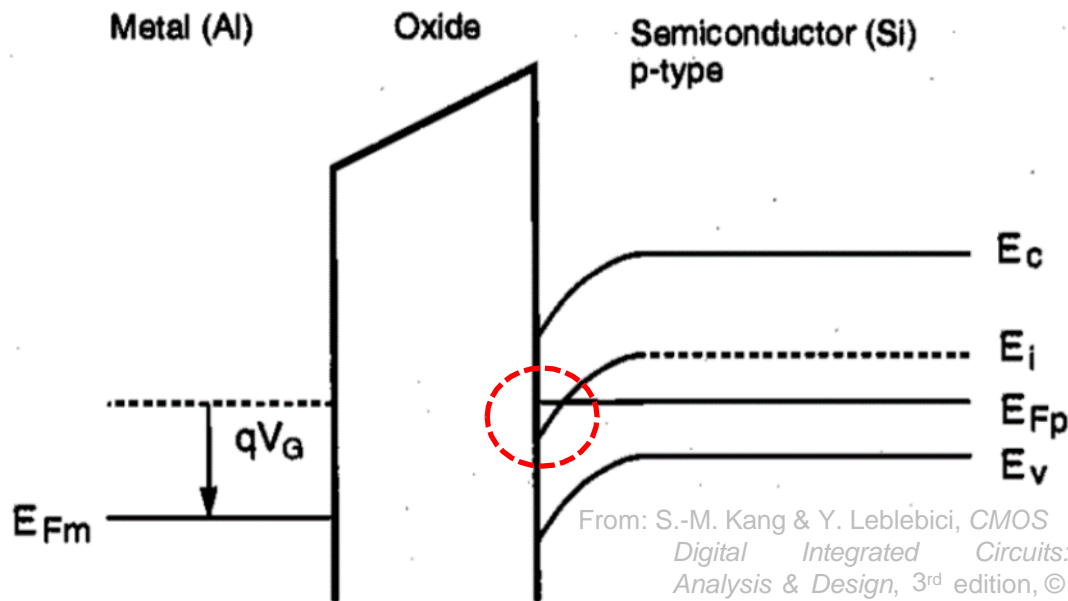


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Energy Band Diagram of MOS

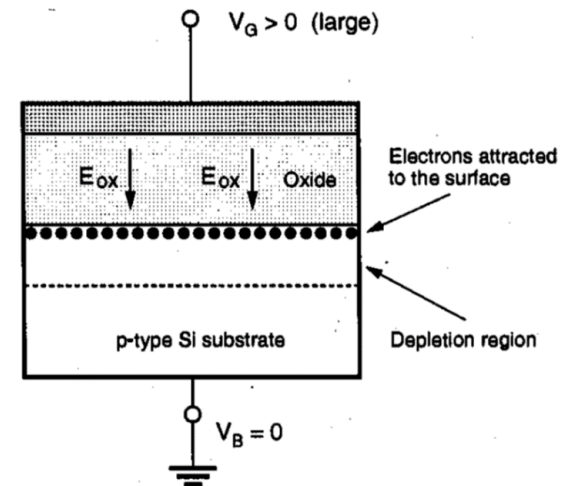
(larger positive voltage at the gate)

- When the positive voltage at the gate is even larger, there is more band bending such that E_{Fp} is now above E_{Fi} .
 - What is the implication?



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EEE201 CMOS Digital Integrated Circuits
Semester 1, 2024/2025 by S.Lam@XJTLU

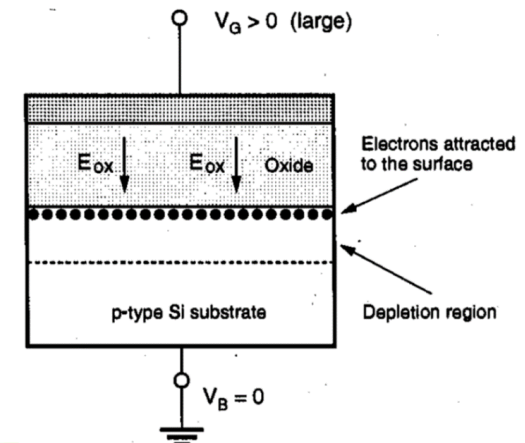
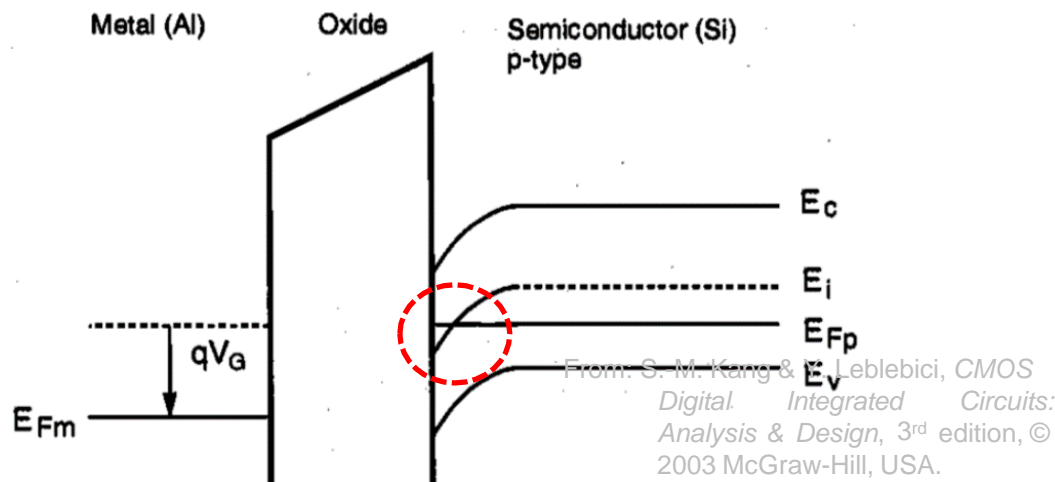


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“Minority” Carriers at Surface

(weak inversion)

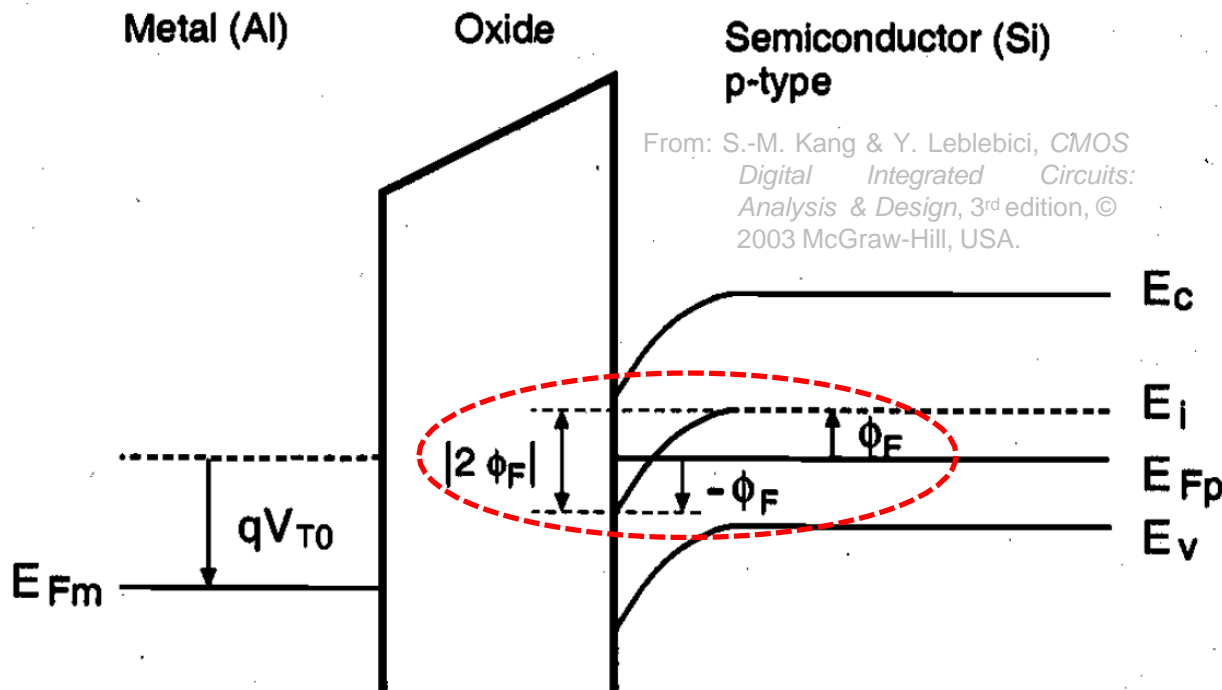
- With E_{Fp} above E_{Fi} in the surface region of the semiconductor, the electrons as the “minority” carriers in the p -type substrate has even higher concentration than the holes.
- There is **inversion** of charge carriers in the surface region of the semiconductor.



“Minority” Carriers at Surface

(strong inversion)

- With a large enough positive V_G , E_{Fp} is now one ϕ_F above E_{Fi} . What is the implication?



➤ It is described as the **surface potential** $\phi_s = |2\phi_F|$

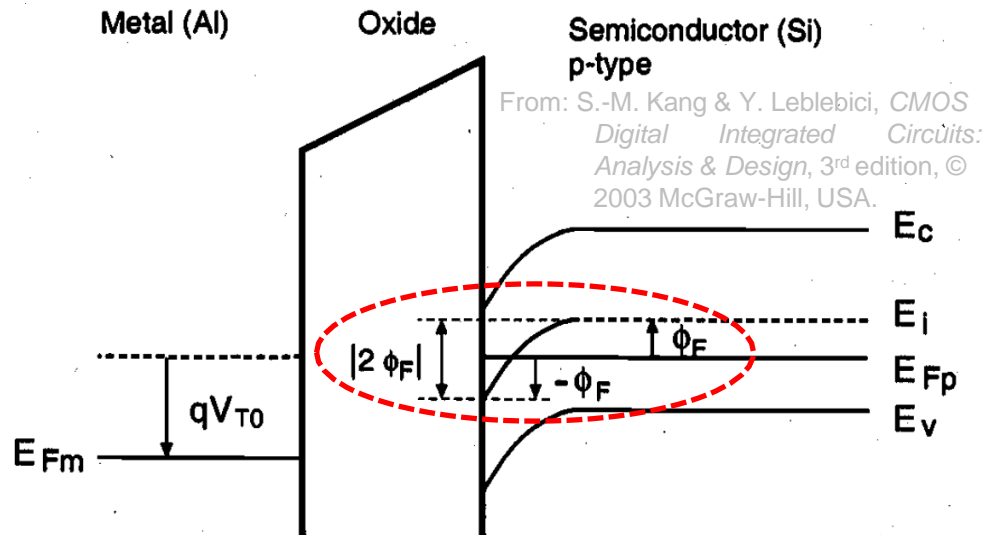
➤ $n_s = p_p \approx N_A$
➤ $n_p \approx n_{i2}/N_A$

- In this situation, it is called **strong inversion**.

Threshold Voltage

(gate voltage for strong inversion)

- ❑ The positive V_G that causes the band bending near the surface of the p -type substrate to have $|\phi_S| = |2\phi_F|$ is called the **threshold voltage** V_T .
 - Do not confuse V_T with the thermal voltage $k_B T/q$.
 - V_T is typically positive for a p -type substrate.



- V_T is typically negative if the MOS structure has an n -type substrate. (Do you know why?)

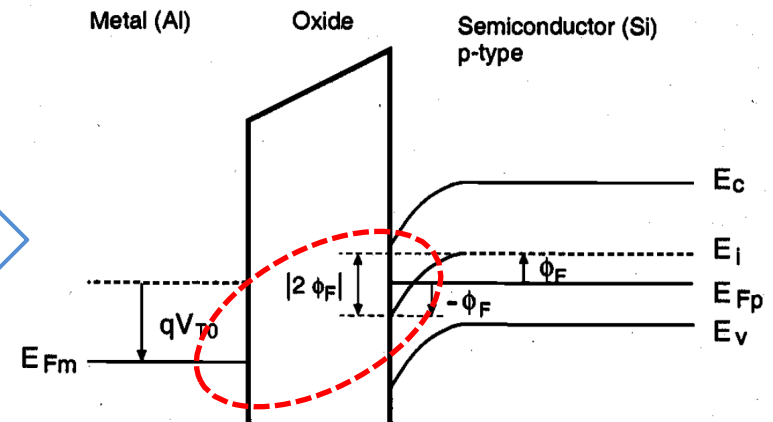
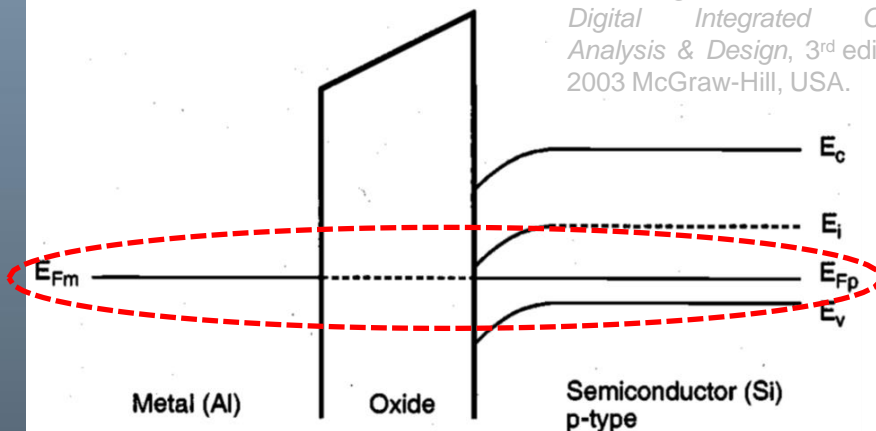
Threshold Voltage

(three components)

- There are typically three components in the **threshold voltage** V_T corresponding respectively the three changes in the energy band diagram.

$$V_T = V_{FB} + 2\phi_F + \frac{\sqrt{2qN_a\epsilon_{Si}(2\phi_F)}}{C_{ox}}$$

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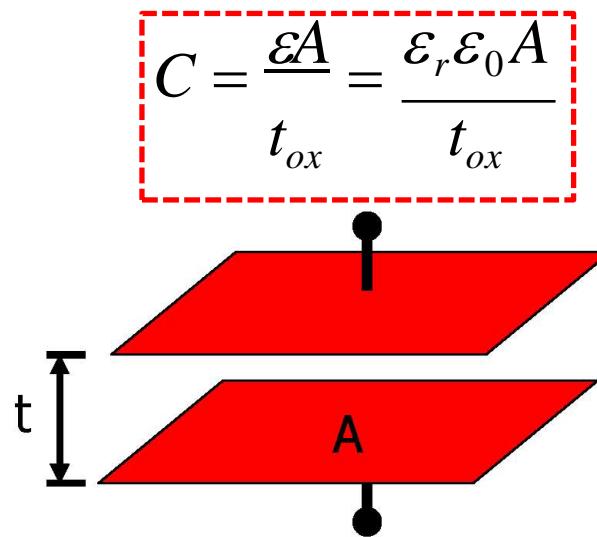
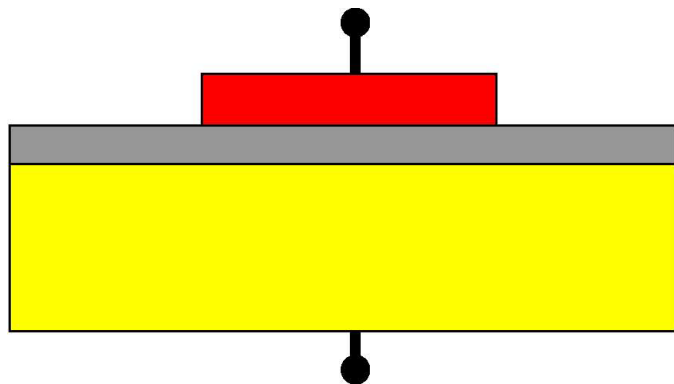


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Capacitance of MOS Structure

(similar structure to parallel-plate capacitor)

- Apparently, the MOS capacitor has a structure of a *parallel-plate* capacitor.



➤ $\epsilon_{r, SiO_2} = 3.9$, $\epsilon_{r, Si} = 11.9$, $\epsilon_0 = 8.85 \times 10^{-14} \text{ F/cm}$

- The **MOS capacitor** has different capacitance behaviour.

➤ voltage dependence

Capacitance of MOS Structure

(voltage dependence)

- ❑ The voltage dependence of the MOS capacitance is because of the change of charges in the surface region of the substrate as the gate voltage varies.
- ❑ In the **accumulation** and **strong inversion** modes, there are respectively charge layers of holes and electrons right underneath the oxide layer;
- ❑ The MOS capacitance in these two modes can be estimated by the parallel-plate capacitance formula:

$$C = \frac{\epsilon A}{t_{ox}} = \frac{\epsilon_r \epsilon_0 A}{t_{ox}}$$

$$\Rightarrow \frac{C}{A} = C_{ox} = \frac{\epsilon_r \epsilon_0}{t_{ox}}$$

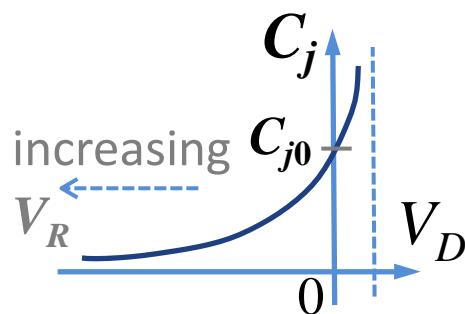


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Capacitance of MOS Structure

(depletion capacitance)

- ❑ In the **depletion mode**, there is neither a layer of electrons nor a layer of holes right underneath the insulating oxide layer.
- ❑ Instead, there is a **depletion region** in which there is a layer of fixed dopant ions (a **space-charge layer**).
 - This is similar to the **depletion region** in the reverse-biased ***p-n* junction**.



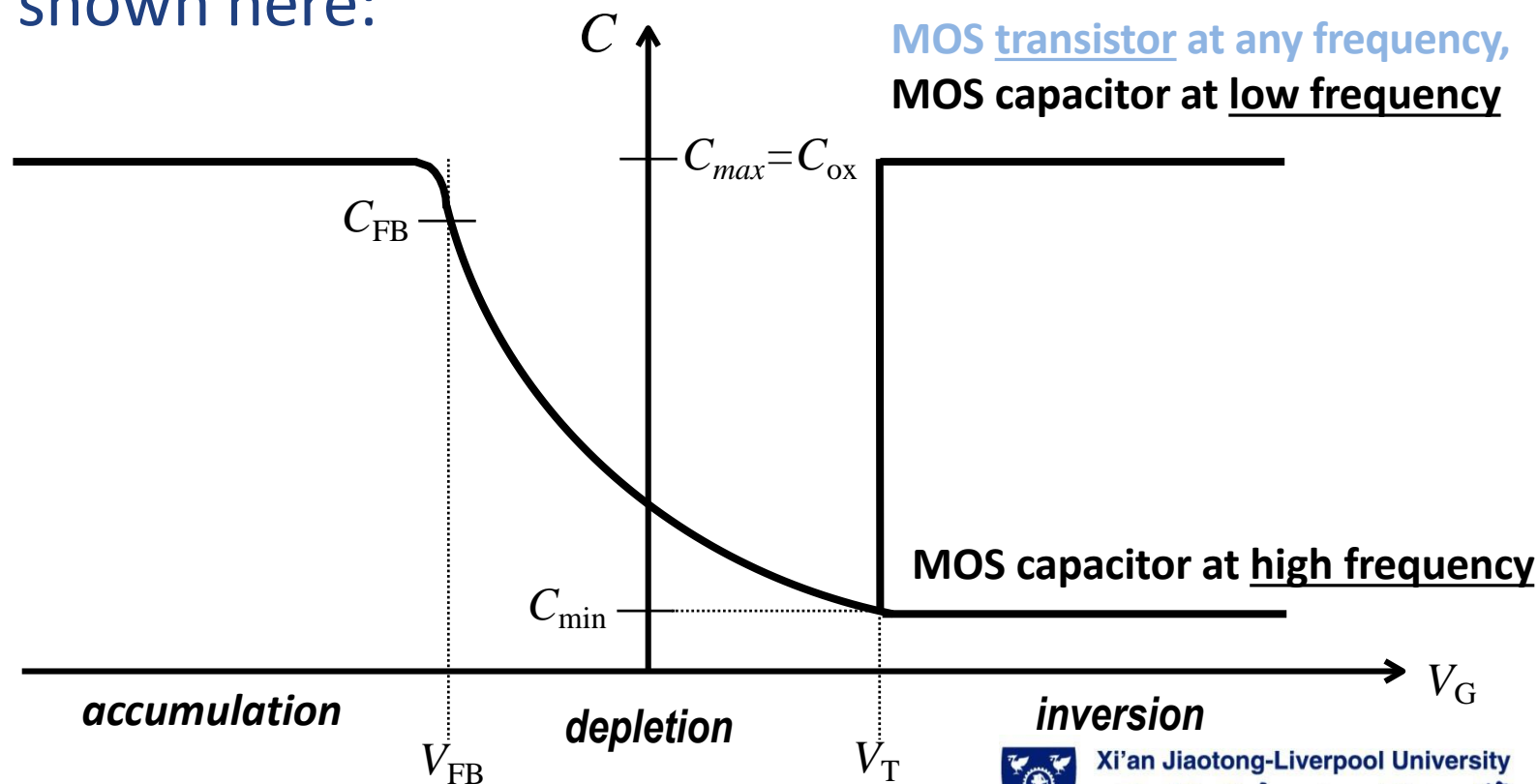
$$C_j = \frac{C_{j0}}{\sqrt{1 + \frac{V_R}{V_{bi}}}}$$

- The **depletion capacitance** decreases as the magnitude of the voltage increases.

Capacitance of MOS Structure

(C-V curves)

- The *voltage-dependent MOS capacitance* of is shown here:

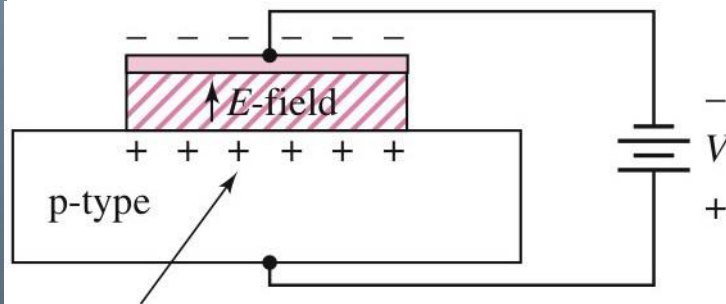


MOS Capacitor – qualitative summary

(accumulation of majority carriers)

- We learn about the **MOS capacitor** with three **operation regions**, depending on the voltage applied to the gate (with the substrate grounded): **accumulation**, **depletion**, and **inversion** (weak & strong inversion).

➤ **accumulation**: majority carriers of the substrate *accumulate* near the surface (oxide-semiconductor interface), with the carrier concentration even higher than the equilibrium concentration.



Accumulation layer of holes

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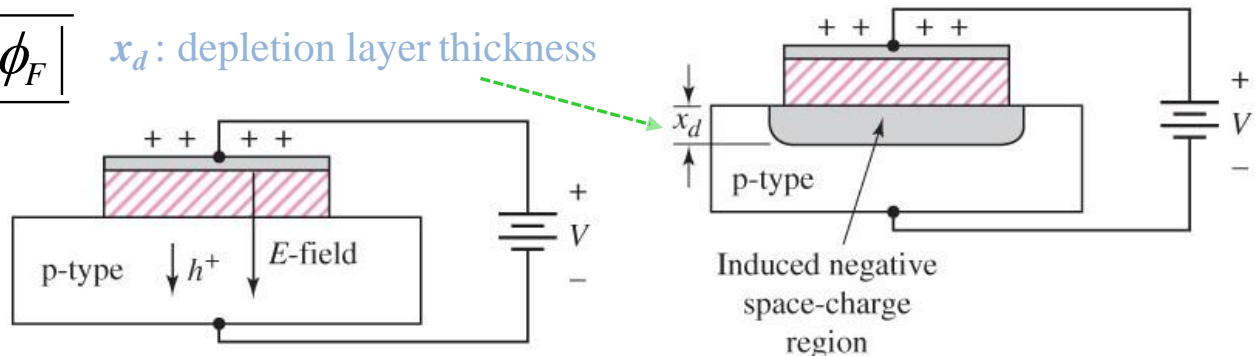
MOS Capacitor – qualitative summary

(depletion region & width)

- **depletion:** majority carriers of the substrate are **depleted** beneath the surface, resulting in a region without any mobile carriers but fixed dopant ions in space; it's called a **depletion region** or **space-charge region**.
- This is similar to the reverse-biased **p-n** junction.

$$x_d = \sqrt{\frac{2\epsilon_{Si}|\phi_s - \phi_F|}{qN_a}}$$

x_d : depletion layer thickness



p-n junction:

$$W_0 = \sqrt{\frac{2\epsilon_{Si}(N_a + N_d)|V_{bias} - V_{bi}|}{eN_aN_d}}$$

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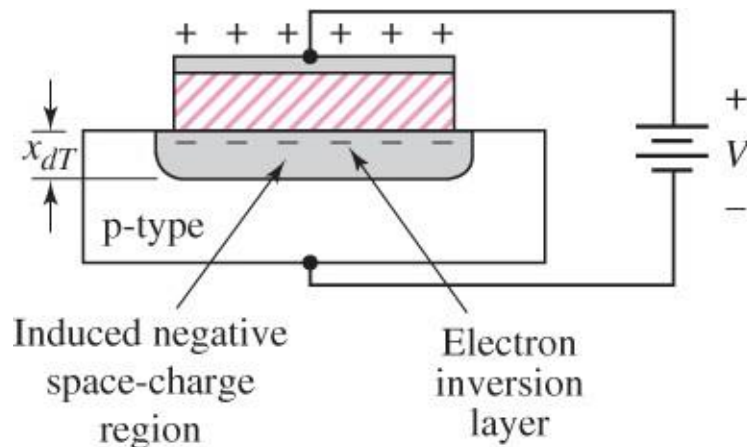


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MOS Capacitor – qualitative summary

(strong inversion)

➤ **inversion**: a very thin charge layer of minority carriers is formed right beneath the surface of the semiconductor when an appropriate gate voltage is applied.



From: Donald A. Neamen, *Microelectronics: Circuit Analysis & Design*, 4th edition, © 2010 McGraw-Hill, USA.

➤ When the **minority carrier concentration** of the **inversion layer** is the same as the majority carrier concentration in the substrate, it is called **strong inversion**.



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MOS Capacitor – qualitative summary

(inversion & threshold voltage)

- At **strong inversion**, the corresponding gate voltage is called the **threshold voltage V_T** :

$$V_T = V_{FB} + 2\phi_F + \frac{\sqrt{2qN_a\epsilon_{Si}(2\phi_F)}}{C_{ox}}$$

- When the minority carrier concentration in the inversion layer is smaller than the majority carrier concentration, it is called **weak inversion**.
- In **weak inversion**, the gate voltage is slightly below the **threshold voltage V_T** .
- This accounts for the **sub-threshold characteristics** of the MOS transistor.

MOS Capacitor – qualitative summary

(2-terminal device)

- If the substrate is not connected to ground but with a biased voltage V_B , V_T needs to be modified as follows (for MOSFET):

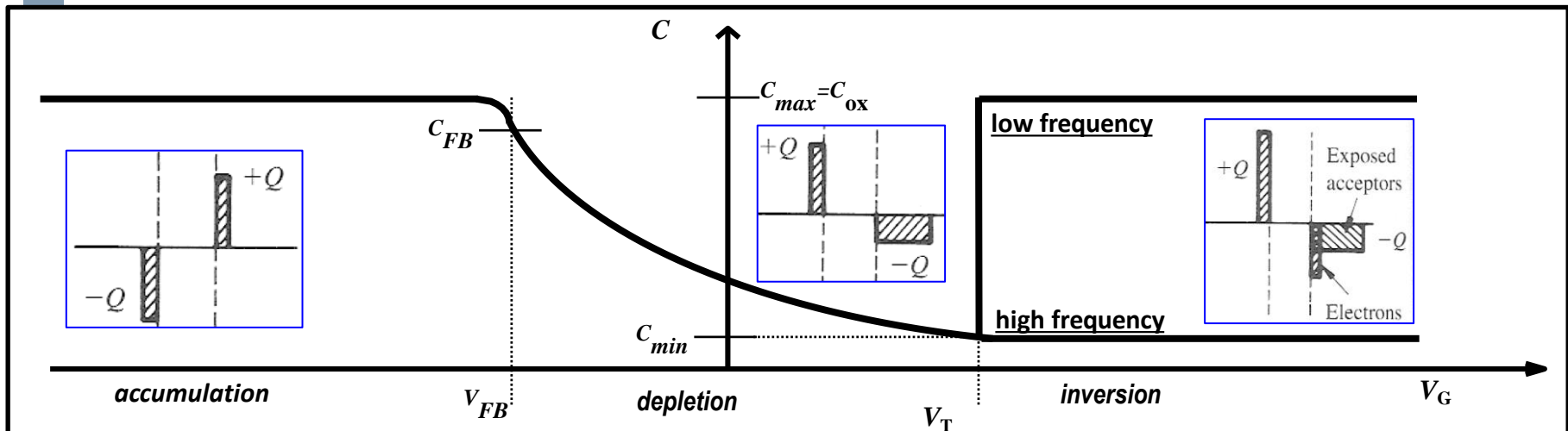
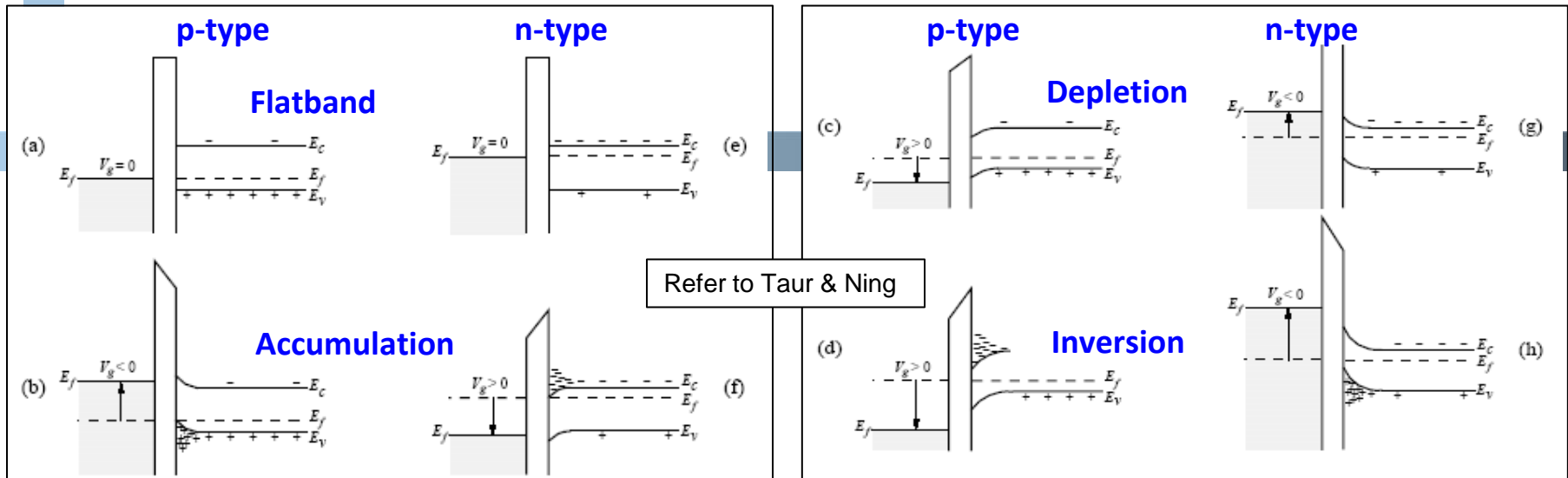
$$V_T = V_{FB} + 2\phi_F + \frac{\sqrt{2qN_A\epsilon_{Si}(2\phi_F - V_B)}}{C_{ox}}$$

- The MOS capacitor is a two-terminal device and it is not very useful by itself in digital ICs.
 - two electrodes: **gate** (denoted by G) & **substrate** (or called **bulk/body**) (denoted by B)
 - The MOS capacitor is however useful in analogue ICs in some circuits as well as CCD image sensors.
 - The **p-n** junction is also a 2-terminal device.



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Summary: MOS Capacitor

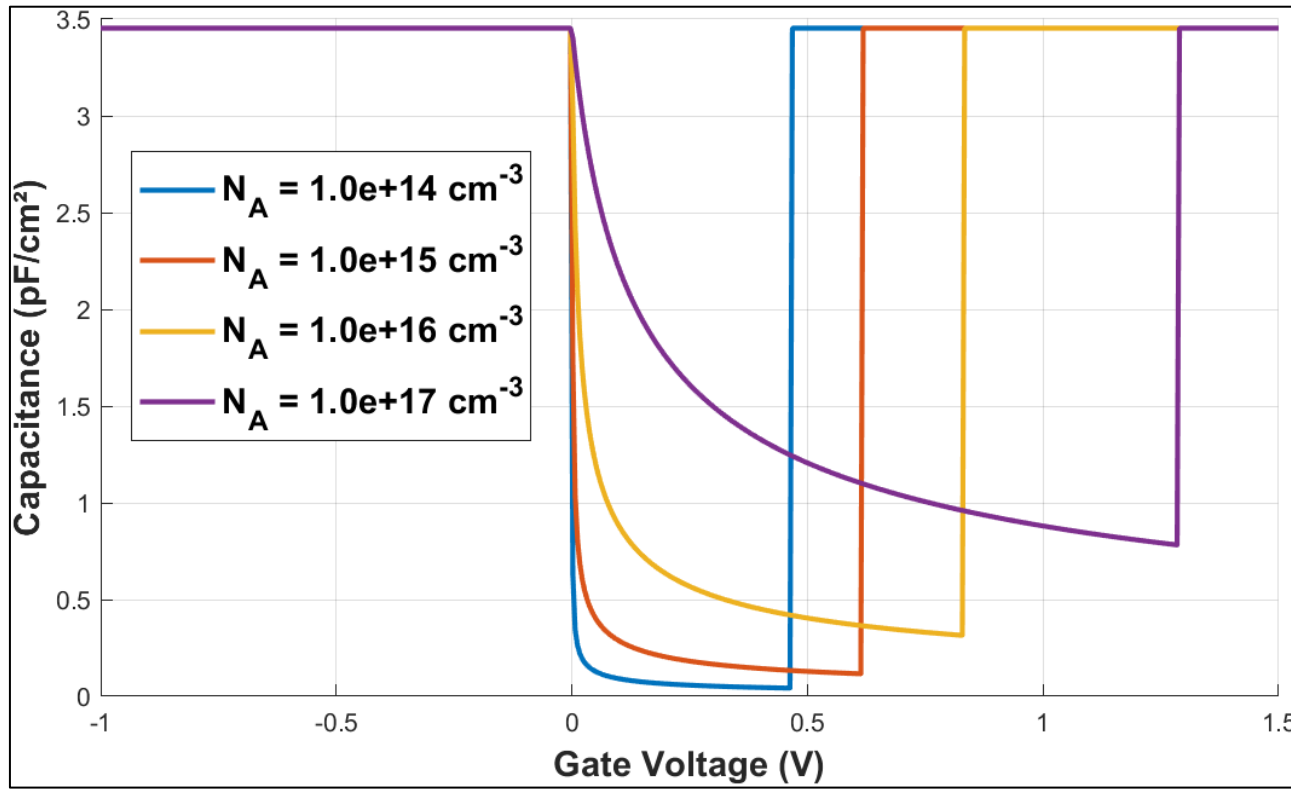


$$V_G = V_{FB} + \phi_s + \frac{\sqrt{2qN_a\epsilon_{Si}(\phi_s)}}{C_{ox}}$$

$$V_T = V_{FB} + 2\phi_F + \frac{\sqrt{2qN_a\epsilon_{Si}(2\phi_F)}}{C_{ox}}$$

ϕ_F = equilibrium Fermi level E_f

Impact of Doping on Low Frequency C-V of MOS Capacitor (p-type)



Observation:

1. $\uparrow N_A \Rightarrow \uparrow V_g$ range of depletion region.
2. $\uparrow N_A \Rightarrow \uparrow C$ in depletion region

Link to the script for calculating capacitance-voltage (C-V):
<https://core.xjtlu.edu.cn/mod/older/view.php?id=38872>

Depletion Mode: $V_{FB} < V_G < V_T$

Gate voltage (V_G)

$$V_G = V_{FB} + 2\phi_s + \frac{\sqrt{2qN_a\epsilon_{Si}(\phi_s)}}{C_{ox}}$$

Threshold voltage (V_T)

$$V_T = V_{FB} + 2\phi_F + \frac{\sqrt{2qN_a\epsilon_{Si}(2\phi_F)}}{C_{ox}}$$

Equilibrium Fermi level (ϕ_F)

$$\phi_F = \frac{kT}{q} \ln\left(\frac{n_i}{p}\right) \approx \frac{kT}{q} \ln\left(\frac{n_i}{N_A}\right)$$

Depletion width (x_d)

$$x_d = \sqrt{\frac{2\epsilon_{Si}|\phi_s|}{qN_a}}$$

Capacitance (C)

$$C_{dep} = \frac{\epsilon_s}{x_d}$$

$$\frac{1}{C} = \frac{1}{C_{ox}} + \frac{1}{C_{dep}}$$